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a semiconductor substrate;

a drain region of a first conductivity type adjacent said semiconductor substrate and comprising a superficial buffer region being more heavily doped than adjacent portions of said drain region;

said superficial buffer region having a dopant concentration of about 5×10^{16} to 5×10^{17} atoms cm⁻³ and the adjacent portions of said drain region having a dopant concentration of about 2.5×10^{15} to 2.5×10^{16} atoms cm⁻³;

a body region surrounded by said superficial buffer region and having a second conductivity type; and

a source region in said body region and having the first conductivity type.

REMARKS

The Examiner is thanked for the thorough examination of the present application. The specification has been amended to correct the noted informalities, as helpfully pointed out by the Examiner. Further, independent Claims 5 and 14 have been amended to more clearly define the subject matter thereof over the prior art. Support for the amendments to Claims 5 and 14 may be found on page 5, lines 3-7 of the originally filed specification, and in FIG. 2b of the drawings, for example. No new matter is being added.

Attached hereto is a marked-up version of the changes made to the specification and claims by the current amendment. The attached pages are captioned "Version with

Markings to Show Changes Made."

In view of the amendments and the supporting arguments presented in detail below, it is submitted that all of the claims are patentable.

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I. The Claimed Invention

The present invention is directed to a lateral diffused metal oxide semiconductor (LDMOS) integrated device. As recited in amended independent Claim 5, for example, the LDMOS device includes a semiconductor substrate and a drain region of a first conductivity type adjacent the semiconductor substrate and including a superficial buffer region being more heavily doped than adjacent portions of the drain region. Moreover, the LDMOS device also includes a body region surrounded by the buffer region and having a second conductivity type, and a source region in the body region and having the first conductivity type. The LDMOS device thus provides a RESURF structure that may be used at relatively high voltages yet with a reduction in punch through problems.

Independent Claim 14 is directed to a related LDMOS integrated device. This claim has similarly been amended to recite that the body region is surrounded by the buffer region as in Claim 5.

II. The Claims Are Patentable

The Examiner rejected independent Claims 5 and 14 over Lidow et al. As perhaps best seen in FIG. 2 of Lidow et al., this patent is directed to a high power vertical diffused MOSFET 20 in which two laterally spaced-apart n+ sources 32, 33 are controlled by a single gate. Each of the sources 32, 33 supply current through channel regions 34, 35 in respective p+ diffusion regions 30, 31. The channel regions 34, 35 lead from source electrodes 23, 24 to a relatively low resistivity, epitaxially-formed drain region (n-) which is deposited on a high conductivity substrate 20a. Immediately adjacent and beneath the gate and in the path from the sources 32, 33 to the drain is a relatively high conductivity n+ region 40, which reduces the on-resistance of the device. Further, the

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breakdown voltage of the device is increased by making the p+diffusions 30, 31 relatively deep and with a large radius of curvature beneath each of the sources 32, 33. These relatively deep regions are referred to as "lower bulk" portions in Lidow et al. (see, e.g., col. 2, lines 17-20).

The Examiner contended that the region 40 and the n+ region 86 in the alternate embodiment illustrated in FIG. 8 of Lidow et al. (which is similar to the region 40) were superficial buffer regions as recited in independent Claims 5 These claims have been amended to recite that the body region is surrounded by the superficial buffer region. In stark contrast, the n+ regions 40, 86 do not surround their respective p+ diffusions regions 30, 31 and 89, 90, as is clearly illustrated in FIGS. 2 and 8 of Lidow et al. Nothing in the specification indicates that these n+ regions would, or even could, ever be extended to surround the entire p+ diffusion regions. In fact, Lidow et al. teaches away from doing so. That is, the relatively deep lower bulk portions of the p+ regions 30, 31 and 89, 90 are specifically formed to have a large radius of curvature in contact with their respective n- drain regions to increase breakdown voltage. See, e.g., col. 4, lines 1-15, and the abstract of Lidow et To surround the p+ diffusion regions 30, 31 and 89, 90 with the n+ regions 40, 86 would eliminate this necessary area of contact with the n- drain.

Instead, the n+ regions 40, 86 are intentionally positioned beneath the gate oxide 25 and between the channels 34, 35 to reduce the forward on resistance of the device. See col. 4, lines 57-64 of Lidow et al. That is, these n+ regions are positioned along the channels to provide vertical current collection and decrease channel resistance. Yet, to somehow surround the p+ regions 30, 31 and 89, 90 with the n+ regions 40, 86 would decrease the voltage capability of the device,

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and thus destroy its operability.

In summary, Lidow et al. fails to teach an LDMOS including a body region surrounded by a superficial buffer region. Moreover, there cannot be any motivation or suggestion to so modify the device of Lidow et al. because to do so would destroy its operability and render the device unsatisfactory for its intended purpose.

Accordingly, it is submitted that independent Claims 5 and 14 are patentable over the prior art. Their respective dependent claims, which recite yet further distinguishing features, are also patentable over the prior art and require no further discussion herein.

CONCLUSIONS

In view of the amendments to the claims and the arguments presented above, it is submitted that all of the claims are patentable. Accordingly, a Notice of Allowance is respectfully requested in due course. Should any minor informalities need to be addressed, the Examiner is encouraged to contact the undersigned attorney at the telephone number listed below.

Respectfully submitted,

OHN F. WOODSON, II

Reg. No. 45,236

Allen, Dyer, Doppelt, Milbrath

& Gilchrist, P.A.

255 S. Orange Avenue, Suite 1401

Post Office Box 3791 Orlando, Florida 32802 Telephone: 407/841-2330

Fax: 407/841-2343

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VERSION WITH MARKINGS TO SHOW CHANGES MADE

In the Specification:

The paragraph beginning at page 4, line 30 has been amended as follows:

The present invention provides a relatively simple and effective solution to punch-through (PT) problems that normally limit the performance of known RESURF LDMOS structures when functioning as high side drivers. This is done without introducing substantial changes in the known RESURF LDMOS structure. The invention is directed to a RESURF LDMOS structure that includes a superficial or surface portion (or body buffer region) 15 of the drain well region 12 which surrounds the body region 13. The body buffer region 15 is preferably more heavily doped than the remaining portion of the drain well region 12, as shown in FIG. 2b. In the drawings, like numbers are used throughout to refer to similar elements for clarity of illustration.

The table beginning at page 6, line 23 has been amended as follows:

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TABLE 1

Region	Dopant	Thickness	Doping [Atoms
		[hw]	cm ⁻³]
p-body (conductivity "P")	boron	0.25-0.75	5x10 ¹⁷ -5x10 ¹⁸
body-buffer	phosphorous	0.15-0.45	$5x10^{16}-5x10^{17}$
(conductivity "N")		<u>below</u>	
		<u>junction</u>	
		with p-body	
drain well region	phosphorous	1.5-4.5	2.5x10 ¹⁵ -2.5x10 ¹⁶
(conductivity "N")		<u>below</u>	
		<u>junction</u>	
		with body-	
		<u>buffer</u>	

The table beginning at page 7, line 1 has been amended as follows:

TABLE 2

region	Dopant	Thickness	Doping [Atoms
		[mm]	cm ⁻³]
n-body (conductivity "N")	phosphorous	0.25-0.75	5x10 ¹⁷ -5x10 ¹⁸
body-buffer (conductivity "P")	boron	0.15-0.45 <u>below</u> <u>junction</u> <u>with n-</u> <u>body</u>	5x10 ¹⁶ -5X10 ¹⁷
drain well region (conductivity "P")	boron	1.5-4.5 <u>below</u> <u>junction</u> <u>with body-</u> <u>buffer</u>	2.5x10 ¹⁵ -2.5x10 ¹⁶

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In the Claims:

Claims 5 and 14 have been amended as follows:

- 5. (Amended) A lateral diffused metal oxide semiconductor (LDMOS) integrated device comprising:
 - a semiconductor substrate;
- a drain region of a first conductivity type adjacent said semiconductor substrate and comprising a superficial buffer region being more heavily doped than adjacent portions of said drain region;
- a body region [in] <u>surrounded by</u> said buffer region and having a second conductivity type; and
- a source region in said body region and having the first conductivity type.
- 15. (Amended) A lateral diffused metal oxide semiconductor (LDMOS) integrated device comprising:
 - a semiconductor substrate;
- a drain region of a first conductivity type adjacent said semiconductor substrate and comprising a superficial buffer region being more heavily doped than adjacent portions of said drain region;
- said superficial buffer region having a dopant concentration of about 5×10^{16} to 5×10^{17} atoms cm⁻³ and the adjacent portions of said drain region having a dopant concentration of about 2.5×10^{15} to 2.5×10^{16} atoms cm⁻³;
- a body region [in] <u>surrounded by</u> said superficial buffer region and having a second conductivity type; and
- a source region in said body region and having the first conductivity type.

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: DIRECTOR, U.S. PATENT AND TRADEMARK OFFICE, WASHINGTON, D.C. 20231, on this 157 day of November, 2002.

Savin & Gelenon